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FORM PTO-1449 INFORMATION DISCLOSURE STATEMENT	ATTY. DOCKET 033082M343	SERIAL NO. To Be Assigned 10/591476
	APPLICANT: Yasuhiko KOJIMA, et al.	
	FILING DATE Herewith	GROUP ART UNIT To Be Assigned

U.S. PATENT DOCUMENTS

*Examiner's Initials		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB- CLASS	FILING DATE, IF APPROPRIATE
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						

FOREIGN PATENT DOCUMENTS

*Examiner's Initials		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB- CLASS	TRANSLATION YES NO	
	AH	63-5424	2/3/88	Japan			Abstract	
	AI	2003-193233	7/9/03	Japan			Abstract	
	AJ							
	AK							
	AL							
	AM							
	AN							
	AO							
	AP							

OTHER INFORMATION (Including Author, Title, Date, Pertinent Pages, Etc.)

AQ	Per Martensson et al., "Growth and Selectivity in the Cu(II) - 2,2,6,6-tetramethyl-3,5-heptanedionate/H ₂ Process", Journal of the Electrochemical Society, 1998, Vol. 145, No. 8, pp. 2926-2931
AR	Mikko Utraiainen, et al., "Studies of metallic thin film growth in an atomic layer epitaxy reactor using M(acac) ₂ (M=Ni, Cu, Pt) precursors, Applied Surface Science, 2000, vol. 157, pp. 151-158
AS	

EXAMINER: /Mandy Louie/	DATE CONSIDERED: 10/13/2009
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

ALL REFERENCES CONSIDERED EXCEPT WHERE LINED THROUGH. /M.L./